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01 Jan 1995

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Chang-Soo Kim Missouri University of Science and Technology, ckim@mst.edu

Dae-Hyuk Kwon

Byung-Woog Cho

Byung-Ki Sohn

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## **Recommended Citation**

C. Kim et al., "A New Approch to Low Drift Ta<sub>2</sub>O<sub>5</sub> by pH Reactive Sputtering and Sol-Gel Method," *Proceedings of the 8th International Conference on Solid-State Sensors and Actuators, 1995 and Eurosensors IX. Transducers '95. (1995, Stockholm, Sweden)*, Institute of Electrical and Electronics Engineers (IEEE), Jan 1995.

The definitive version is available at https://doi.org/10.1109/SENSOR.1995.721989

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## A NEW APPROCH TO LOW DRIFT Ta<sub>2</sub>O<sub>5</sub> pH-ISFET BY RF REACTIVE SPUTTERING AND SOL-GEL METHOD

Dae-Hyuk Kwon\*, Byung-Woog Cho\*\*, Chang-Soo Kim\*\*\* and Byung-Ki Sohn\*\*\*

\* Dept. of Electronic Eng., Kyungpook Sanup University, 33 Buho-ri, Hayang-up, Kyungsan-gon, Kyungsang buk-do, 713-900, KOREA.

\*\* Dept. of Electronic Eng., Kyungpook National University, KOREA.

\*\*\* Sensor Technology Research Center, Kyungpook National University, KOREA.

### SUMMARY

Thin films, such as SiO<sub>2</sub>,  $ZrO_2$ ,  $Al_2O_3$ ,  $Si_3N_4$  and  $Ta_2O_5$ , were known as hydrogen ion sensing membranes for pH-ISFET[1]. Among them,  $Ta_2O_5$  thin film was reported to have the better sensing characteristics than those of other hydrogen ion sensing membranes.

In this research, the Ta<sub>2</sub>O<sub>5</sub> hydrogen ion sensing membrane were formed by RF reactive sputtering and Sol-Gel method. Ta<sub>2</sub>O<sub>5</sub> pH-ISFETs by RF reactive sputtering and Sol-Gel method showed a good linearity in wide pH range(pH 2 to 12) and had high sensitivities of 58~59mV/pH and 57mV/pH, respectively. Especially, Ta<sub>2</sub>O<sub>5</sub> pH-ISFET by RF reactive sputtering showed stable long-term sensitivity(57~59mV/pH) during 45 days and long-term stability during 60 days (0.05pH/day).

## RF REACTIVE SPUTTERING METHOD

Table 1 is the optimum conditions for the formation of the  $Ta_2O_5$  membrane by RF reactive sputtering. The conditions were determined from investigation on the physical properties(refractive index, etching ratio, dielectric constant and composition ratio) and electrical properties (C-V characteristics and leakage current) of the

RF power	50W
Working pressure	50mtorr
Gas mixture ratio(Ar/O <sub>2</sub> )	4: 1 sccm
Substrate temp.	200°C
Annealing conditions	O <sub>2</sub> , 400℃, 1hr

Table 1.  $Ta_2O_5$  sputtering and annealing conditions[2].

thin films.

Hydrogen ion sensing characteristics of the  $Ta_2O_5$  pH-ISFET by RF reactive sputtering is shown in figure 1. This sensor showed a good linearity within the wide pH range (pH 2 to 12) and high sensitivity (about 59mV/pH), which was very close to the theoretical Nernst potential.

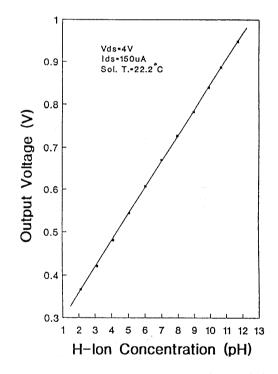


Figure 1. Hydrogen ion sensing characteristics of Ta<sub>2</sub>O<sub>5</sub> pH-ISFET by RF reactive sputtering.

The long-term stabilities of the pH-ISFET measured in the pH 7 solution are shown in figure 2. The pH-ISFET annealed by conditions shown in table 1 had the best stability of about 0.05pH/day during 60 days. XRD analysis showed that the crystal

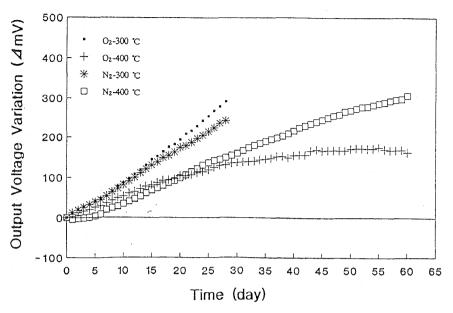


Figure 2. Long-term stabilities of the Ta<sub>2</sub>O<sub>5</sub> pH-ISFET by RF reactive sputtering.

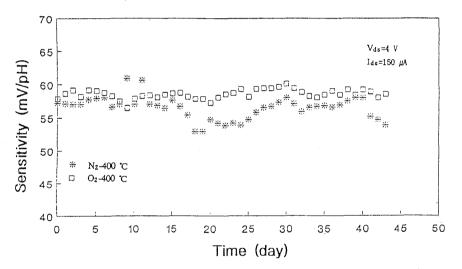


Figure 3. Long-term sensitivities of Ta<sub>2</sub>O<sub>5</sub> pH-ISFET by RF reactive sputtering.

structure of the annealed  $Ta_2O_5$  film was changed from amorphous to poly-crystalline structure in the vicinity of 500 °C.

As shown in figure 3, the long-term sensitivities of pH-ISFET annealed in O<sub>2</sub> ambient was maintained at about 57~59mV/pH, while that of pH-ISFET annealed in N<sub>2</sub> ambient much varied with time.

## SOL-GEL METHOD

From the previous results, we can see that the

Ta<sub>2</sub>O<sub>5</sub> gate pH-ISFET by RF sputtering has the better sensing characteristics than the results of the reference[3], but it needs to be still improved in the long-term stability. The dominant factor of the drift will be the hydration or memory effect of the membrane[4]. If the ultra-thin membrane is formed, paradoxically the hydration will be completed within a very short time, and the above-mentioned problems may be solved. In this work, we tried to form the ultra-thin Ta<sub>2</sub>O<sub>5</sub> membrane by using Sol-Gel method. The solution for the fabrication of Ta2O5 films is prepared as

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described in figure 4. The prepared solution was spin-on coated on the Si<sub>3</sub>N<sub>4</sub> gate pH-ISFET and heat-treated at 400°C to remove the remaining organics. The membrane formed with this process had ultra-thin thickness(about 100Å), which was measured by ellipsometric method. Figure 5 is XRD patterns of Ta<sub>2</sub>O<sub>5</sub> film according to heat treatment conditions. The film showed a amorphous structure with heat treatment temperature below 600°C, while poly-crystalline structure was formed by heat treatment at 800°C in the O2 ambience. We determined heat treatment conditions to be  $400^{\circ}C(O_2 \text{ ambience, } 1 \text{ hour})$ because the leakage currents began to increase in the films annealed above 400°C. Figure 6 is an AES depth profile of Ta<sub>2</sub>O<sub>5</sub> thin film heat-treated at 400°C. This figure shows that oxygen, the sensing site for hydrogen ions, is more rich at the surface than in the bulk.

Hydrogen ion sensing characteristics of  $Ta_2O_5$ pH-ISFET by Sol-Gel method are shown in figure 7. This sensor showed a good linearity in the wide pH range(pH 2 to 12) and high sensitivity(about 57mV/pH). From these results, we see that  $Ta_2O_5$  thin film by Sol-Gel method can be applied to hydrogen ion sensing membrane.

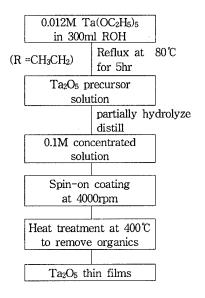


Fig. 4. Flow diagram for the fabrication of  $Ta_2O_5$  thin films

## CONCLUSION

The Ta<sub>2</sub>O<sub>5</sub> pH-ISFET by RF reactive sputtering had a good linearity in the wide pH range(pH 2 to 12), high sensitivity(about  $58 \sim 59 \text{mV/pH}$ ), stable long-term stability(about 0.05 pH/day), and good

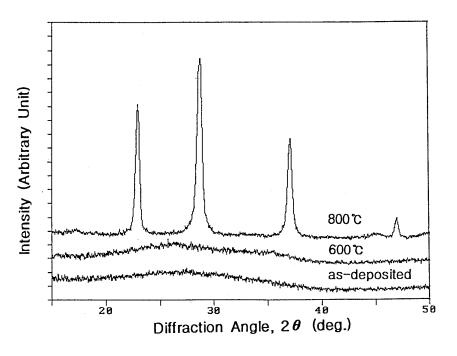


Figure 5. XRD patterns of Ta<sub>2</sub>O<sub>5</sub> films

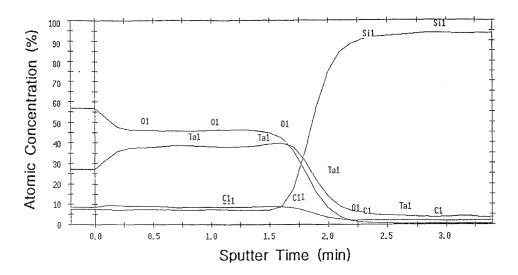


Figure 6. AES depth profile of Ta<sub>2</sub>O<sub>5</sub> films

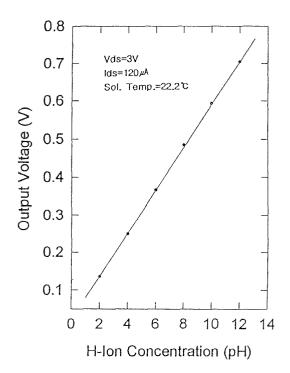


Figure 7. Hydrogen ion sensing characteristics of Ta<sub>2</sub>O<sub>5</sub> pH-ISFET by Sol-Gel method.

long-term sensitivity(57~59mV/pH). These results were better than those of previously reported papers[3].

In this reseach, we tried to form ultra-thin Ta<sub>2</sub>O<sub>5</sub> membrane for improving the drift of pH-ISFET by Sol-Gel method. By introducing Sol-Gel method, Ta<sub>2</sub>O<sub>5</sub> film having about 100Å thick was formed. This sensor showed a good linearity and high sensitivity(about 57 mV/pH) in the range of pH 2 to 12. From above result, we see that Ta<sub>2</sub>O<sub>5</sub> membrane by Sol-Gel method can be used in the hydrogen ion sensig membrane.

More detailed studies are now in progess to improve the long-term stability by Sol-Gel method.

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